



Attorney's Docket No. 5308-157IP2

PATENT

1762  
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor: Das et al.

Confirmation No.: 3570

Serial No.: 10/045,542

Group Art Unit: 1762

Filed: October 26, 2001

Examiner: Michael. E. Barr

For: METHOD OF FABRICATING AN OXIDE LAYER ON A SILICON CARBIDE  
LAYER UTILIZING AN ANNEAL IN A HYDROGEN ENVIRONMENT

Date: September 21, 2004

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

**UNDER 37 C.F.R. § 1.97(b)**

Sir:

Attached is a list of documents on form PTO-1449 together with copies of each identified document. This Information Disclosure Statement is submitted in accordance with 37 C.F.R. § 1.97(c), before final Office Action or Allowance, whichever is earlier.

In accordance with the requirements of 37 C.F.R. § 1.97(c)(2), a check for the \$180.00 fee specified in 37 C.F.R. § 1.17(p) is enclosed. This amount is believed to be correct; however, the Commissioner is authorized to charge any deficiency or credit any overpayment to Deposit Account No. 50-0220.

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Respectfully submitted,

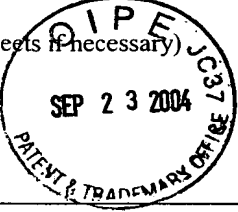
Timothy J. O'Sullivan  
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**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on September 21, 2004.

  
Traci A. Brown

<b>FORM PTO-1449</b> U.S. Department of Commerce Patent and Trademark Office				Attorney Docket Number 5308-157IP2		Serial No. 10/045,542	
<b>LIST OF DOCUMENTS CITED BY APPLICANT</b> (Use several sheets if necessary)							
				Applicants: Das et al.			
				Filing Date: October 26, 2001		Group 1762	
<b>U. S. PATENT DOCUMENTS</b>							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
<b>FOREIGN PATENT DOCUMENTS</b>							
		Document Number	Date	Country	Class	Subclass	Translation Yes   No
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
	1	Wang et al. "The Effects of NH <sub>3</sub> Plasma Passivation on Polysilicon Thin-Film Transistors," <i>IEEE Electron Device Letters</i> , Vol. 16, No. 11, November 1995, pp. 503-5.					

EXAMINER

\*EXAMINER

DATE CONSIDERED

Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.